

**MOVABLE BODY DRIVE SYSTEM AND MOVABLE BODY DRIVE
METHOD, PATTERN FORMATION APPARATUS AND METHOD,
EXPOSURE APPARATUS AND METHOD, DEVICE MANUFACTURING
METHOD, AND DECISION-MAKING METHOD**

ABSTRACT

A drive device drives a wafer table in a Y-axis direction based on a measurement value of an encoder that measures position information of the wafer table (WTB) in the Y-axis direction and based on known correction information in accordance with position information of the wafer table (WTB) in non-measurement directions (e. g. Z, ez and ex directions) that are measured by interferometers (16, 43A are 43B) at the time of the measurement by the encoder. That is, the wafer table (a movable body) is driven in the Y-axis direction based on the measurement value of the encoder that has been corrected by correction information for correcting a measurement error of the encoder that is caused by a relative displacement of a head and a scale in the non-measurement direction. Accordingly, the movable body can be driven with high accuracy in a desired direction while measuring the position by the encoder, without being affected by the relative motion between the head and the scale in directions other than a direction to be measured (measurement direction).

Figures 11A and 11B